

Study of Pull-in Voltage in MEMS Actuators

Prashant D.Hanasi^{#1}, B. G. Sheeparamatti^{*2}, Kirankumar B.B^{#3}

Basaveshwar Engineering College, Bagalkot, Department of Electronics and Communication, Karnataka, INDIA

Prashanthanasi8790@gmail.com sheepar@yahoo.com kiranb4004@gmail.com

Introduction: As the voltage bias increases from zero across a pair of parallel plates, the distance between such plates would decrease until they reach 2/3 of the original spacing, at which point the two plates would be suddenly snapped into contact. This behavior is called the pull-in effect. And the voltage that is required for this pull-in operation to take place is called the pull-in voltage..

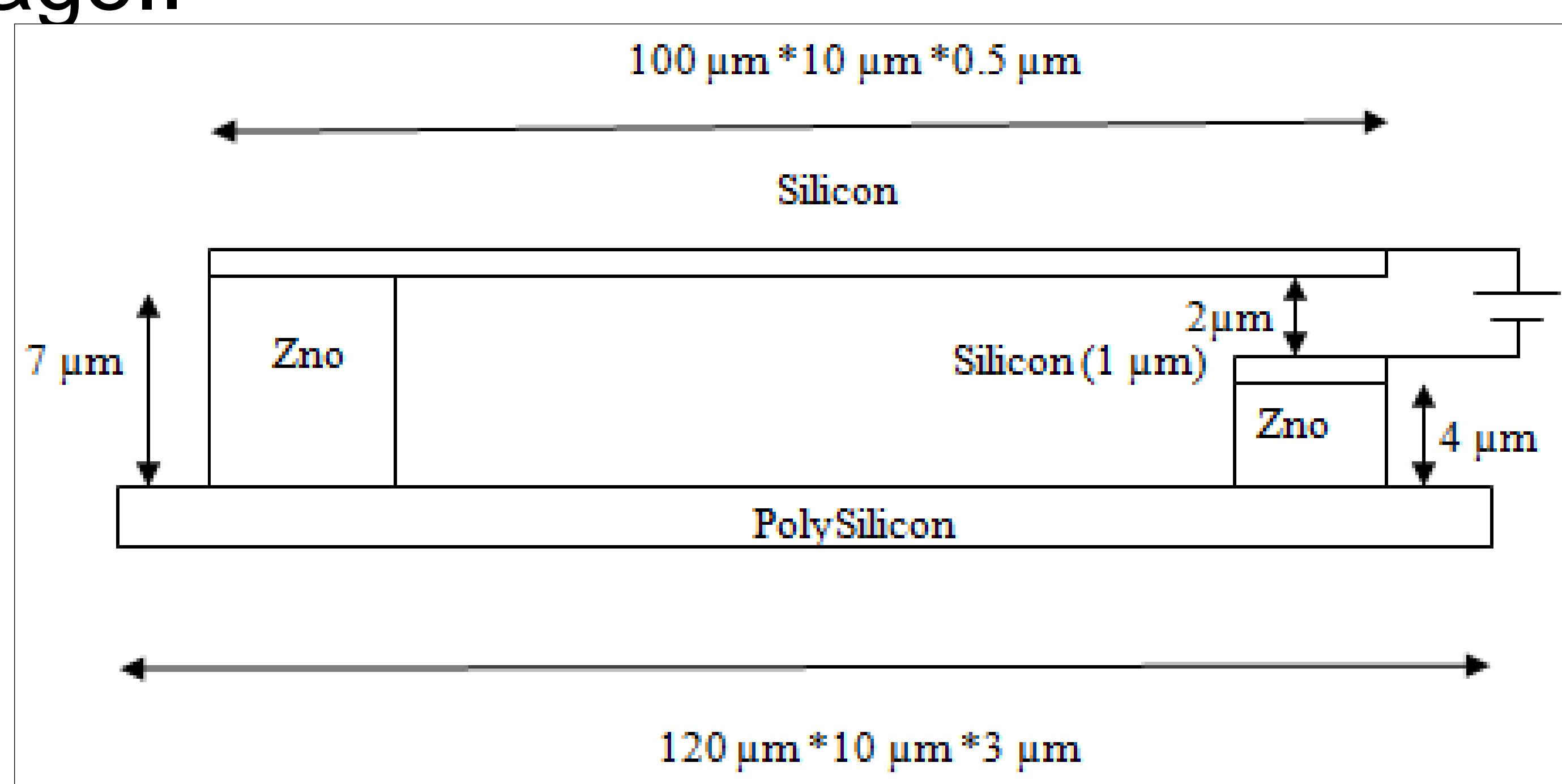


Figure 1. Schematic diagram of MEMS actuator

Pull-in voltage(V_{pi}) calculation:

The stiffness constant of the actuator is given by

$$K = \frac{EWt^3}{4L^3} \dots (1)$$

The pull-in voltage equation is given by

$$V_{pi} = \sqrt{\frac{8kd^3}{27\epsilon_0 A}} \dots (2)$$

Features of Actuators:

Variable	Value	Units
Length	100	μm
Width	10	μm
thickness	0.5	μm
density	2329	Kg/m ³
Poison's ratio	0.28	

Results: Therotical calculation can be made using the equation 7 and 8 we will get the stiffness constant as K=0.0531 N/m and V_{pi} as 3.77V. And simulated value of pull-in voltage is 19.7V.

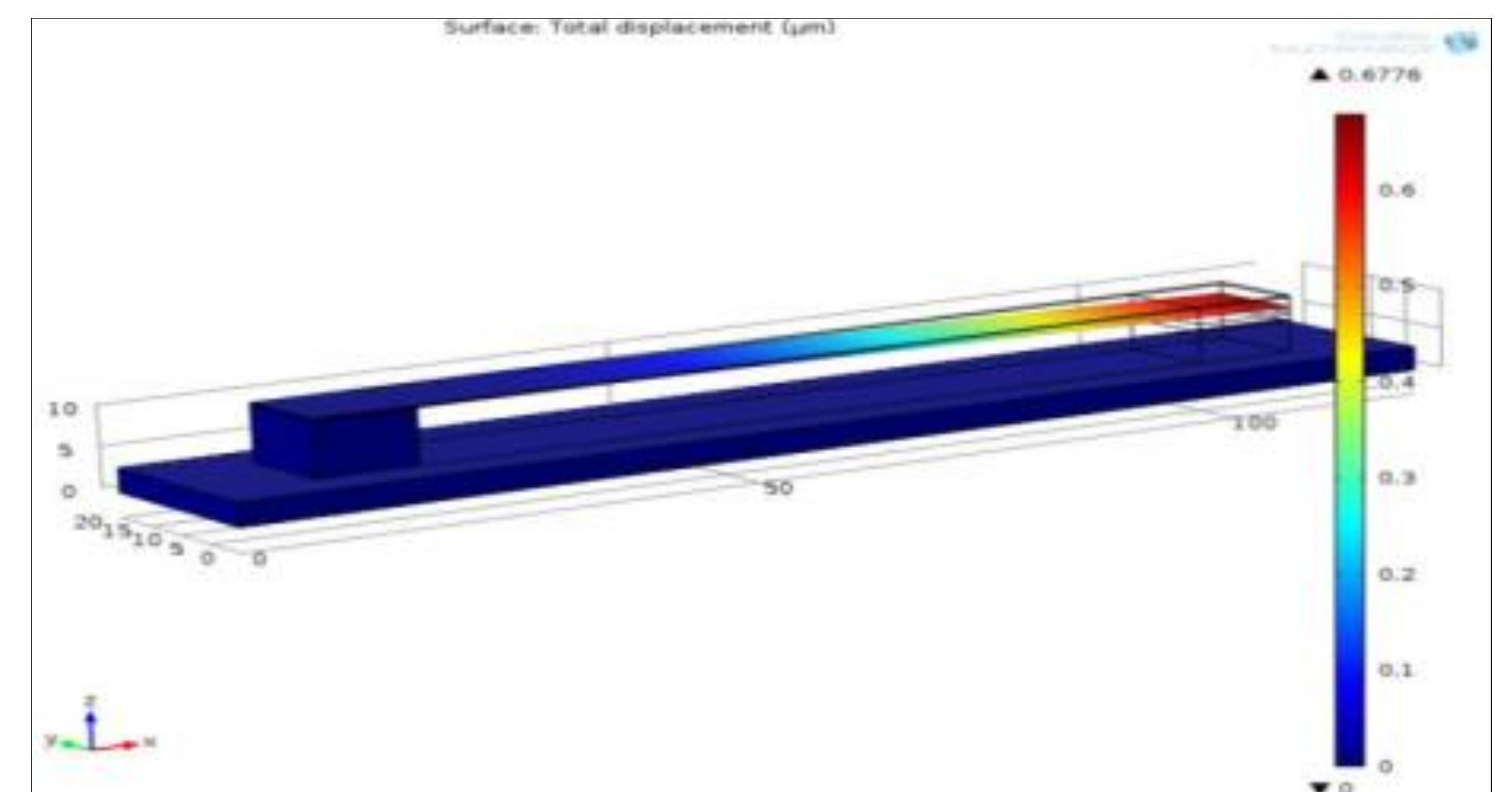


Figure 2. Simulated model of MEMS actuator

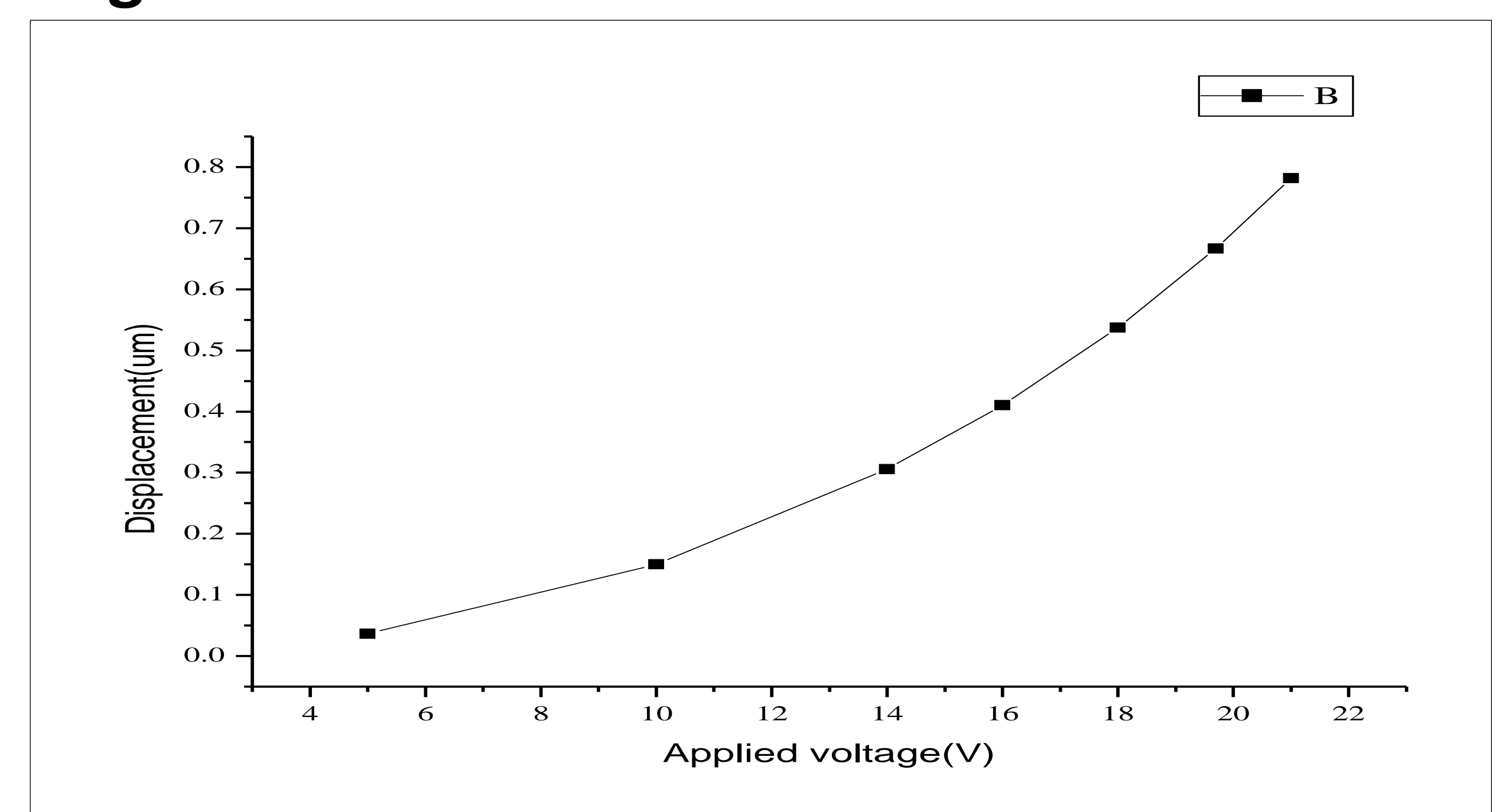


Figure 3. Deflection v/s applied voltage

Conclusions: V_{pi} can be reduced by increasing the area of actuator, and also by reducing gap and thickness of actuator and hence v_{pi} reduced 19.7V to 12.1 V.

References:

1. Foundations of MEMS by chang liu 4th chapter electrostatic sensing actuation.
2. Design of low actuation voltage RF MEMS Switch Serigo P.Pacheo¹ Linda P.B.Katehi¹ Clark T-C.Nguyen²
3. Performance Analysis and Optimization of Lumped Parameters of Electrostatic Actuators for Optical MEMS Switches by D M.Madheswaran , International Journal of Computer Science and Information Security, Vol. 7, No. 1, 2010